

PROCEEDINGS OF SPIE

# ***Advances in X-Ray/EUV Optics and Components X***

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*Editors*

**11–12 August 2015  
San Diego, California, United States**

*Sponsored and Published by*  
SPIE

**Volume 9588**

Proceedings of SPIE 0277-786X, V. 9588

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Advances in X-Ray/EUV Optics and Components X, edited by Shunji Goto, Christian Morawe, Ali M. Khounsary,  
Proc. of SPIE Vol. 9588, 958801 · © 2015 SPIE · CCC code: 0277-786X/15/\$18 · doi: 10.1117/12.2217992

Proc. of SPIE Vol. 9588 958801-1

The papers in this volume were part of the technical conference cited on the cover and title page. Papers were selected and subject to review by the editors and conference program committee. Some conference presentations may not be available for publication. Additional papers and presentation recordings may be available online in the SPIE Digital Library at [SPIDigitalLibrary.org](http://SPIDigitalLibrary.org).

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Author(s), "Title of Paper," in *Advances in X-Ray/EUV Optics and Components X*, edited by Shunji Goto, Christian Morawe, Ali M. Khounsary, Proceedings of SPIE Vol. 9588 (SPIE, Bellingham, WA, 2015) Six-digit Article CID Number.

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781628417548

Published by

**SPIE**

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) • Fax +1 360 647 1445

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## Introduction

This volume contains papers presented at the conference on "Advances in X-Ray/EUV Optics and Components X," which was held in San Diego, California, United States on 11–12 August 2015 as part of the SPIE 2015 International Symposium on Optics + Photonics.

The conference was composed of five oral sessions: Multilayers, Focusing, Optics Development and Fabrication, Instrumentation and Imaging, and Optics for Coherent Sources. The final session was held jointly with the conference on "X-ray Lasers and Coherent X-Ray Sources: Development and Application XI."

The focus of the conference was technological developments in X-ray/EUV optics for synchrotron and FEL beamlines. Presentations covered a wide spectrum, from vacuum ultra violet to hard X-rays. Topics related to X-ray lasers, coherent X-ray sources, laboratory-based X-ray sources, and X-ray imaging were presented in independent conferences at the same symposium.

Scheduled for nearly one and a half days of oral presentations with an accompanying evening poster session, the conference was lively and well attended. We would like to thank the authors, speakers, session and joint session chairs, program committee members, the conference participants for their contributions, and the SPIE staff for their help in organizing the conference.

**Shunji Goto**  
**Christian Morawe**  
**Ali M. Khounsary**

